# **Special Issue**

# Metasurface-Based Devices and Systems

## Message from the Guest Editors

Metasurfaces represent a groundbreaking approach to controlling electromagnetic waves, enabling unprecedented functionalities and so on. These two-dimensional structures, composed of subwavelength-scale elements, have become a cornerstone in modern photonics and optoelectronics, transforming applications in imaging, sensing, and beyond. We are pleased to announce this Special Issue dedicated to "Metasurface-Based Devices and Systems". We invite high-quality reviews, original research articles, and interdisciplinary contributions that address topics including but not limited to the following: Design, simulation, and optimization of novel metasurfaces.

Applications in imaging, sensing, and communication technologies.

Advances in tunable, reconfigurable, and multifunctional metasurfaces.

Material innovations and scalable fabrication methods for metasurfaces.

Integration of metasurfaces into optoelectronic and photonic systems.

### **Guest Editors**

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## Deadline for manuscript submissions

31 December 2025



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# Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

#### Editor-in-Chief

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